

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)	Confirmation No. 9528
Koichiro TANAKA)	
Application No. 10/769,820)	Examiner: Samuel Heinrich
Filed: February 3, 2004)	Group Art Unit: 1725
For: LASER IRRADIATION STAGE, LASER)	
IRRADIATION OPTICAL SYSTEM, LASER)	
IRRADIATION APPARATUS, LASER)	
IRRADIATION METHOD, AND METHOD OF)	
MANUFACTURING A SEMICONDUCTOR)	Date: November 8, 2006
DEVICE)	

AMENDMENT

MAIL STOP AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed August 8, 2006, please amend the above-identified patent application as follows:

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 7 of this paper.